

Notice of References Cited	Application/Control No. 10/070,286	Applicant(s)/Patent Under Reexamination BENZEL ET AL.	
	Examiner Anita K Alanko	Art Unit 1765	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-5,352,635	10-1994	Tu et al.	438/53
	C	US-2004/0195096	10-2004	Tsamis et al.	204/426
	D	US-5,139,624	08-1992	Searson et al.	205/656
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	N	RU 2099813 C1	12-1997	Russian Federat	PEREVOSHCHIKOV et al.	H01L 21/308
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	U	Lammel, G. et al "Free-standing, mobile 3D porous silicon microstructures" Sensors and Actuators A Physical, 85, pp 356-360, August 25, 2000.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.